



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**Applicant:** 

Daggett et al.

Serial No.:

10/628,598

Filed:

July 28, 2003

For:

LIQUID COATING DEVICE

WITH BAROMETRIC

PRESSURE COMPENSATION

Examiner:

Unknown

Group Art Unit: Unknown

Docket No.:

FSI0041/US/3

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 I CERTIFY THAT ON

IS BEING DEPOSITED WITH THE U.S. POSTAL SERVICE AS FIRST CLASS MAIL IN AN ENVELOPE ADDRESSED TO THE

COMMISSIONER FOR PATENTS, P.O. BOX 1450, ALEXANDRIA,

VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

The documents listed on the enclosed Form PTO-1449 are presented pursuant to Applicant's duty of disclosure under 37 C.F.R. 1.56. A copy of each of these documents is enclosed.

No fee is believed to be necessary for the consideration of this Information Disclosure Statement since it is being filed before the receipt of an Office Action on the merits. In case the papers cross in the mail, it is requested that consideration of this Information Disclosure Statement be given under 37 C.F.R. § 1.97 (c)(2). If any fee is required, please charge our Deposit Account No. 50-1775 and notify us of the same.

Respectfully Submitted,

Daniel C. Schulte, Reg. No. 40,160

33072

PATENT TRADEMARK OFFICE Phone: 651-275-9806

Facsimile: 651-351-2954

Dated: Ochober 3 2003

#9745

PTO-1449 U.S. Department of Commerce Atty. Docket No. Serial No. Patent and Trademark Office FSI0041/US/3 10/628,598 **Applicant** INFORMATION DISCLOSURE Daggett et al. STATEMENT BY APPLICANT Filing Date Group July 28, 2003 **U.S. PATENT DOCUMENTS** Document Class Filing Date Examiner Date Name Subclass Initial Number If Appropriate 06/1990 4,932,353 Kawata et al. 5,127,362 07/1992 Iwatsu et al. 5,211,753 05/1993 Swain 11/1994 5,366,757 Lin 05/1995 Konishi et al. 5,416,047 5,626,679 05/1997 Shimizu et al. 5,766,671 06/1998 Matsui 6,177,133 01/2001 Gurer et al. 6,599,560 07/2003 Daggett et al. FOREIGN PATENT DOCUMENTS Document Translation Name Date Country Class **Subclass** Number Yes/No 3-178123 08/1991 Abstract Japan 4-94525 03/1992 Japan Abstract 05-144721 06/1993 Japan Abstract OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.) Uchiyama, Photoresist Application Device, JP 5-144721 (English Translation), June 1993, pp. 1-10 Gürer, et al. "Model-based adaptive process control: A CD-control example." Solid State Technology, pp. 205-206, 208, 210, 212 (July 1996) Gürer, et al., "...Adaptive Process Control in Lithography," Semicon Korea 98, Semicon Korea Technical Symposium 98, Process & Evaluation Technology I, II, pp. 205-218 EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.